

MATERIAL DATABASE

ALD MATERIALS TESTED WITH DALP®

#	MATERIAL	PREC. A	PREC. B	GROWTH RATE (Å/PASS)	CHARACTERIZATION	USE
1	Pt ^(a)	(MeCp)PtMe ₃	O ₃	0.55 – 1	IE, SEM, EDX, TEM, XRD, XPS, LEIS, R(T)	Mirrors
2	Al ₂ O ₃	DMAI	H ₂ O	0.3	IE, SEM, EDX, TEM, XPS	Dielectric, Barrier, Protection
3	TiO ₂ ^(a)	Ti(O ⁱ Pr) ₄	H ₂ O	0.1 – 0.6	IE, SEM, EDX, TEM, XPS, transistor	Optical, Dielectric, Barrier, Protection
4	ZnO ^(b)	Zn(dmap) ₂	H ₂ O	0.7 – 1.5	IE, SEM, EDX, AFM, XRD, XPS, transistor	Optoelectronics
5	CuO	Cu(hfac) ₂	H ₂ O	0.06	IE, SEM, EDX, XRD	Photovoltaic
6	Ir	(EtCp)Ir(CHD)	O ₃		IE, SEM, EDX, XRD	Conductor
7	IrO ₂	(EtCp)Ir(CHD)	O ₃		IE, SEM, EDX, XRD	Electrochromic devices
8	HfO ₂	Hf(NMe ₂) ₄	H ₂ O	1.1 – 1.6	IE	Dielectric
9	SnO ₂	TDMASn	H ₂ O	0.8	SEM, EDX, I-V curve	Gas sensors, Transparent electrodes, solar cells
10	V ₂ O ₅	TEMAV	H ₂ O		Validated	thermochromic windows; Electrochromic device
11	WO ₃	Wawona™	O ₃		Upcoming	anti-bacterial & self-cleaning surfaces
12	MgF ₂	Magna™	O ₃	0.4 – 0.6	Validated	Anti-reflective coatings, UV optics
13	Ga ₂ O ₃	Galaj™	O ₃		Upcoming	Power Electronics
14	Nb ₂ O ₃	Nautilus2™	O ₃		Upcoming	Batteries

Would you like to know if your materials are compatible with our technology? [Request a demo](#)